

IFW

PATENT



**IN THE UNITED STATES PATENT
AND TRADEMARK OFFICE**

Applicant: Hyug-Jin Kwon
Serial No.: 10/615,062
Filed: July 8, 2003
Title: BATCH TYPE ATOMIC LAYER
DEPOSITION APPARATUS
AND IN-SITU CLEANING
METHOD THEREOF
Group Art Unit: 1763
Examiner: Sylvia MacArthur
Attorney Docket No.: 29926/39496

I hereby certify that this paper is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, Virginia 22313-1450, on **September 15, 2005**.



Sandip H. Patel (Reg. No. 43,848)
Attorney for Applicant

**AMENDMENT "A" AND
RESPONSE TO OFFICIAL ACTION**

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Dear Sir:

In response to the non-final official action dated June 15, 2005, please amend the above-identified patent application as set forth herein.

Amendments to the claims begin on page 2 of this paper.

Remarks begin on page 5 of this paper.